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Docket No.: 9323.051.00-US

(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

In Kwon JEONG

Customer No.: 30827

Application No.: 09/931,695

Confirmation No.: 3412

Filed: August 16, 2001

Art Unit: 1753

For: SYSTEM AND METHOD FOR PROCESSING

SEMICONDUCTOR WAFERS USING **DIFFERENT WAFER PROCESSES**

Examiner: Brian L. Mutschler

MS AF Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

<u>AMENDMENT</u>

Sir:

In response to the Final Office Action dated August 19, 2004, please amend the patent application identified above as follows:

INTRODUCTORY COMMENTS

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks begin on page 10 of this paper.